

Notice of References Cited

Application/Control No.

09/978,155

Applicant(s)/Patent Under
Reexamination
HUNG, CHI-YUAN

Examiner

Kripa Sagar

Art Unit

1756

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	B	US-6,107,006	08-2000	Chang, Wen-Pin	430/322
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Handbook of VLSI Microlithography; ed:J.N.Helbert, Noyes (2001), pp.729-755
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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